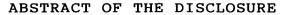
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The present invention provides a scanning electron microscope that can obtain a high-precision SEM image and width measurement values, without damaging an object to be measured even at a high This scanning electron microscope magnification. irradiates a sample with an electron beam so as to detect secondary electrons released from the sample due to the irradiation. The scanning electron microscope also includes scan generators for detecting the secondary electrons at a frequency depending on a detection magnification for the The present invention also provides a method of measuring a pattern size using the above scanning electron microscope.